



PTO/SB/08a/b (08-03)

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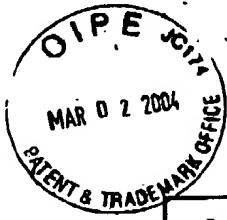
Substitute for form 1449A/B/PTO				Complete if Known	
				Application Number	09/938,644-Conf. #1172
				Filing Date	August 27, 2001
				First Named Inventor	Neal Rueger
				Art Unit	1765
				Examiner Name	T. Mackey Alanko
Sheet	1	of	2	Attorney Docket Number M4065.0466/P466	

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number Number-Kind Code <sup>2</sup> (#known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
JKS	A	5,976,347	11/1999	Wakabayashi et al.	
	B	6,103,399	8/2000	Smela et al.	
	C	5,972,193	10/1999	Chou et al.	

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (#known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
					T <sup>6</sup>

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. <sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. <sup>3</sup>Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			
JKS	C1	MARC SCHAEPKENS et al.; "Asymmetric microtrenching during inductively coupled plasma oxide etching in the presence of a weak magnetic field", Applied Physics Letters, Vol. 72, Number 11, March 16, 1998. pp 1293-5			T <sup>2</sup>
	C2	K. DONOHOE; "Aspect Ratio-Plasma Effects" March 14, 2000.			
	C3	"Introduction to Microengineering, Mask Design", <a href="http://www.dbanks.demon.co.uk/ueng/maskdes.html">http://www.dbanks.demon.co.uk/ueng/maskdes.html</a> accessed July 3, 2001.			
	C4	"Introduction to Microengineering, LIGA", <a href="http://www.dbanks.demon.co.uk/ueng/liga.html">http://www.dbanks.demon.co.uk/ueng/liga.html</a> accessed July 3, 2001.			
	C5	"Introduction to Microengineering, Excimer laser micromachining", <a href="http://www.dbanks.demon.co.uk/ueng/excimerum.html">http://www.dbanks.demon.co.uk/ueng/excimerum.html</a> accessed July 3, 2001.			
	C6	"Introduction to Microengineering, Wafer bonding", <a href="http://www.dbanks.demon.co.uk/ueng/waferbond.html">http://www.dbanks.demon.co.uk/ueng/waferbond.html</a> accessed July 3, 2001.			
	C7	"Introduction to Microengineering, Electrochemical etching of silicon", <a href="http://www.dbanks.demon.co.uk/ueng/electrochem.html">http://www.dbanks.demon.co.uk/ueng/electrochem.html</a> accessed July 3, 2001.			
	C8	"Introduction to Microengineering, Surface micromachining", <a href="http://www.dbanks.demon.co.uk/ueng/surfum.html">http://www.dbanks.demon.co.uk/ueng/surfum.html</a> accessed July 3, 2001.			
	C9	"Introduction to Microengineering, Basic Structures", <a href="http://www.dbanks.demon.co.uk/ueng/sistruct.html">http://www.dbanks.demon.co.uk/ueng/sistruct.html</a> accessed July 3, 2001.			
	C10	"Introduction to Microengineering, Lift off", <a href="http://www.dbanks.demon.co.uk/ueng/liftoff.html">http://www.dbanks.demon.co.uk/ueng/liftoff.html</a> accessed July 3, 2001.			
	C11	"Introduction to Microengineering, Dry Etching", <a href="http://www.dbanks.demon.co.uk/ueng/dryetch.html">http://www.dbanks.demon.co.uk/ueng/dryetch.html</a> accessed July 3, 2001.			
	C12	"Introduction to Microengineering, Wet etching", <a href="http://www.dbanks.demon.co.uk/ueng/wetetch.html">http://www.dbanks.demon.co.uk/ueng/wetetch.html</a> accessed July 3, 2001.			
	C13	"Introduction to Microengineering, Thin films", <a href="http://www.dbanks.demon.co.uk/ueng/Thinfilms.html">http://www.dbanks.demon.co.uk/ueng/Thinfilms.html</a> accessed July 3, 2001.			



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Substitute for form 1449A/B/PTO				<i>Complete If Known</i>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(Use as many sheets as necessary)</i>				Application Number	09/938,644-Conf. #1172
Sheet	2	of	2	Filing Date	August 27, 2001
				First Named Inventor	Neal Rueger
				Art Unit	1765
				Examiner Name	T. Mackey <i>Aianko</i>
				Attorney Docket Number	M4065.0466/P466

<i>Asif</i>	C14	"Introduction to Microengineering, Basic techniques", <a href="http://www.dbanks.demon.co.uk/ueng/sitech.html">http://www.dbanks.demon.co.uk/ueng/sitech.html</a> accessed July 3, 2001.	
	C15	"Integrated MicroElectroMechanical Systems", <a href="http://www.mdl.sandia.gov/micromachine/integrated.html">http://www.mdl.sandia.gov/micromachine/integrated.html</a> accessed July 3, 2001.	
	C16	"Summit Technology", <a href="http://www.mdl.sandia.gov/micromachine/trilevel.html">http://www.mdl.sandia.gov/micromachine/trilevel.html</a> accessed July 3, 2001.	
	C17	"MEMS Overview", <a href="http://www.mdl.sandia.gov/micromachine/overview.html">http://www.mdl.sandia.gov/micromachine/overview.html</a> accessed July 3, 2001.	
<i>↓</i>	C18	"Vision for MEMS", <a href="http://www.mdl.sandia.gov/micromachine/vision.html">http://www.mdl.sandia.gov/micromachine/vision.html</a> accessed July 3, 2001.	
	C19	PHILIP BALL; "Honey, I shrunk the cogs", <a href="http://www.nature.com/nsu/010111/010111-3.html">http://www.nature.com/nsu/010111/010111-3.html</a> July 12, 2001.	

Examiner Signature	<i>Anita K. Manley</i>	Date Considered	4/9/04
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<sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.

*H&K* "Optical microrotors" <http://www.physicstoday.org/pt/vol-54/iss-3/p9.html>, accessed 7/12/01.